

Description of Reference Numerals on the Drawings

100	electron beam treatment apparatus
120	vacuum chamber
122	large-area cathode
124	high-voltage insulator
125	substrate
126	anode
127	gas manifold
128	cathode cover insulator
129	high-voltage power supply
130	wafer or substrate holder
131	low-voltage power supply
132	variable leak valve
135	vacuum pump
136	electron generation and acceleration region
138	ionization region
242	positive ions
244	electrons
300	feedback control circuit
366	integrator
390	sense resistor
392	unity gain voltage follower
394	variable gain resistor
396	amplifier
398	variable leak valve controller
400	electron beam treatment apparatus
410	shelf
415	space
420	vacuum chamber
422	large-area cathode
424a	upper insulator

424b	lower insulator
426	Anode
436	electron generation and acceleration region
510	array of holes
522	large-area cathode
524	high-voltage insulator
526	anode
560	array of holes
576	anode